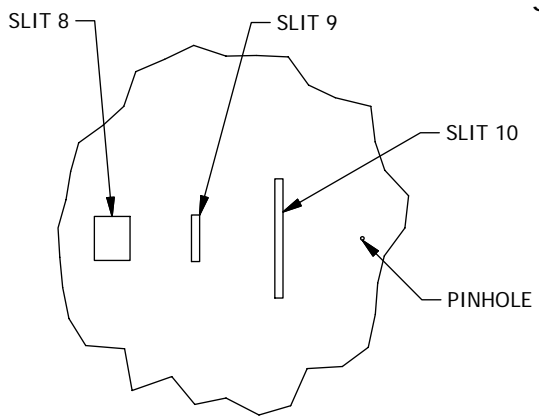
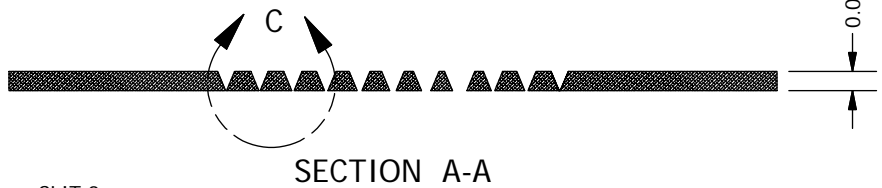


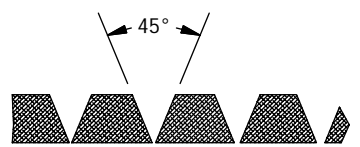
GENERAL NOTES
 1. Precision air slits in 0.025 thick silicon with 0.0002-0.0005 thick nickel plating both sides.

APERTURE NOTES
 1. All slits centered vertically
 2. 1103 μm horizontal center to center
 3. 45° included angle through material

APERTURE GEOMETRY (left to right)
 1. 32 μm wide X 580 μm high slit
 2. 47 μm wide X 580 μm high slit
 3. 79 μm wide X 580 μm high slit
 4. 110 μm wide X 580 μm high slit
 5. 158 μm wide X 580 μm high slit
 6. 221 μm wide X 580 μm high slit
 7. 315 μm wide X 580 μm high slit
 8. 473 μm wide X 580 μm high slit
 9. 110 μm wide X 615 μm high slit
 10. 110 μm wide X 1600 μm high slit
 11. ∅ 47 μm circular pinhole



**DETAIL B
SCALE 10 : 1**



**DETAIL C
SCALE 10 : 1**

**THE OBSERVATORIES
OF THE CARNEGIE INSTITUTION OF WASHINGTON**
 813 Santa Barbara Street
 Pasadena, CA 91101

MATERIAL See notes			UNLESS OTHERWISE SPECIFIED FRACTIONAL DECIMAL ANGULAR +/- 1/32 .XX +/- 0.01 +/- 0.1 DEG .XXX +/- 0.002 GOAL .XXX +/- 0.005 REQD BREAK SHARP EDGES MACHINED SURFACES 125 ✓ ALL DIMENSIONS IN INCHES			
EST WEIGHT			P lanet F inder S pectrograph Slit Mask			
SCALE 4:1						
DWN	CRANE	5/8/2006	SHEET A	DRAWING NUMBER PFS06001	SHT 1 OF 1	REV 2
APVD	BY	DATE				

1	1	Slit Mask
ITEM	QTY	DESCRIPTION
Bill of Material		